

Highly resistive HVPE-GaN grown on native seeds – investigation and comparison of different dopants

Motivation

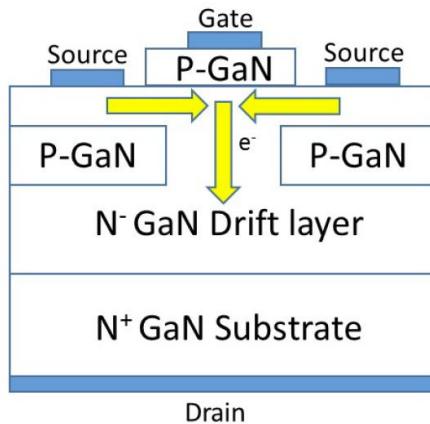
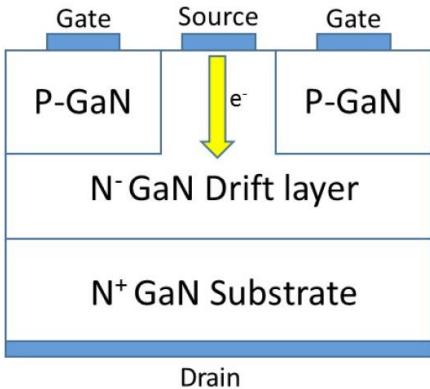
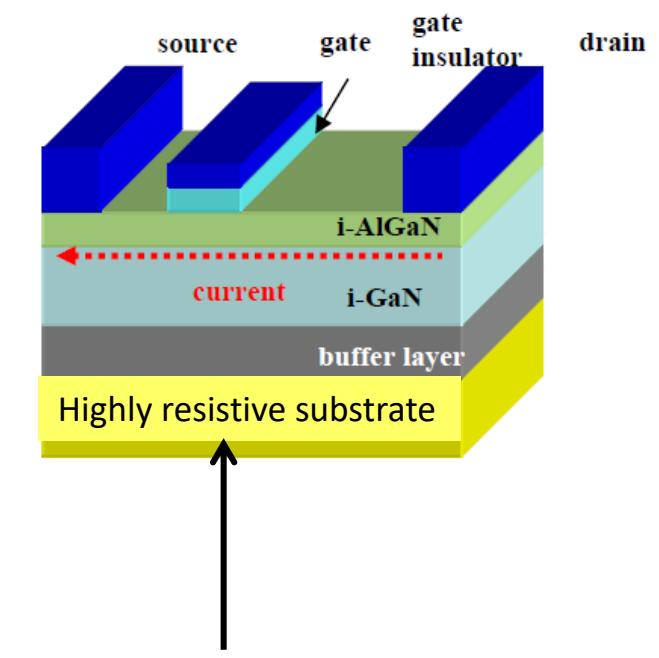


Figure 1: Two possible FET topologies. The arrows indicate the direction of electron flow.

Vertically operating

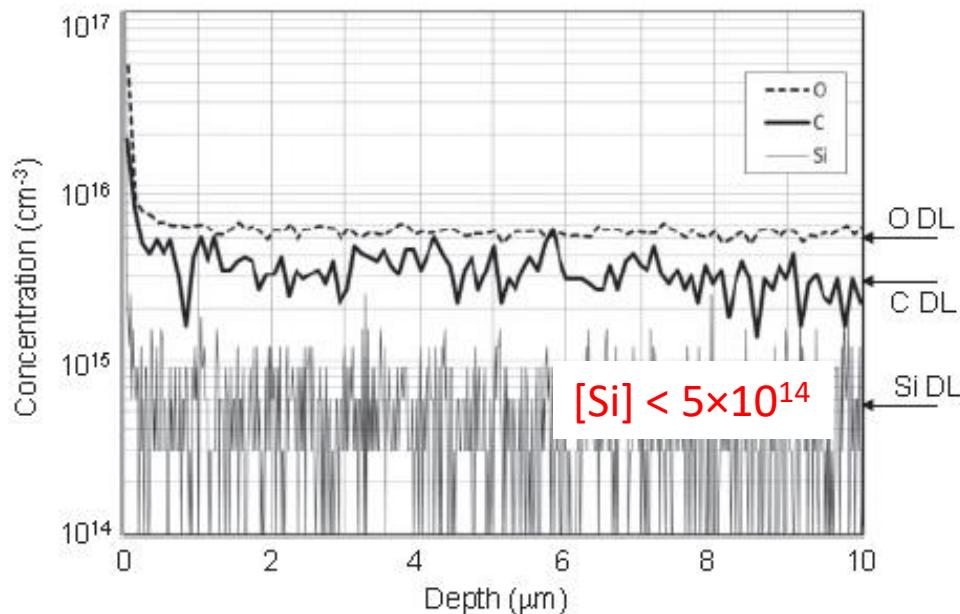


Laterally operating

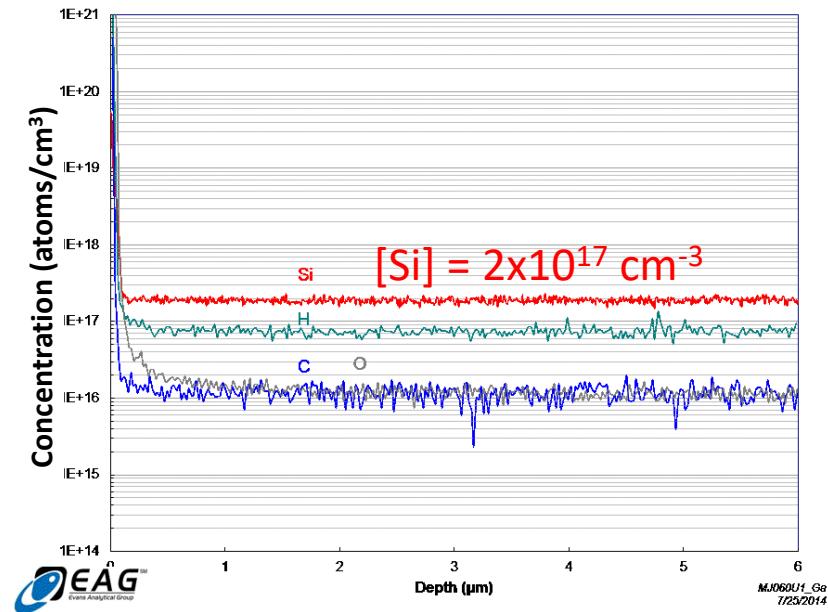
Undoped HVPE-GaN



Quartz-free reactor
 $\rho = 1 \times 10^9 \Omega \cdot \text{cm}$

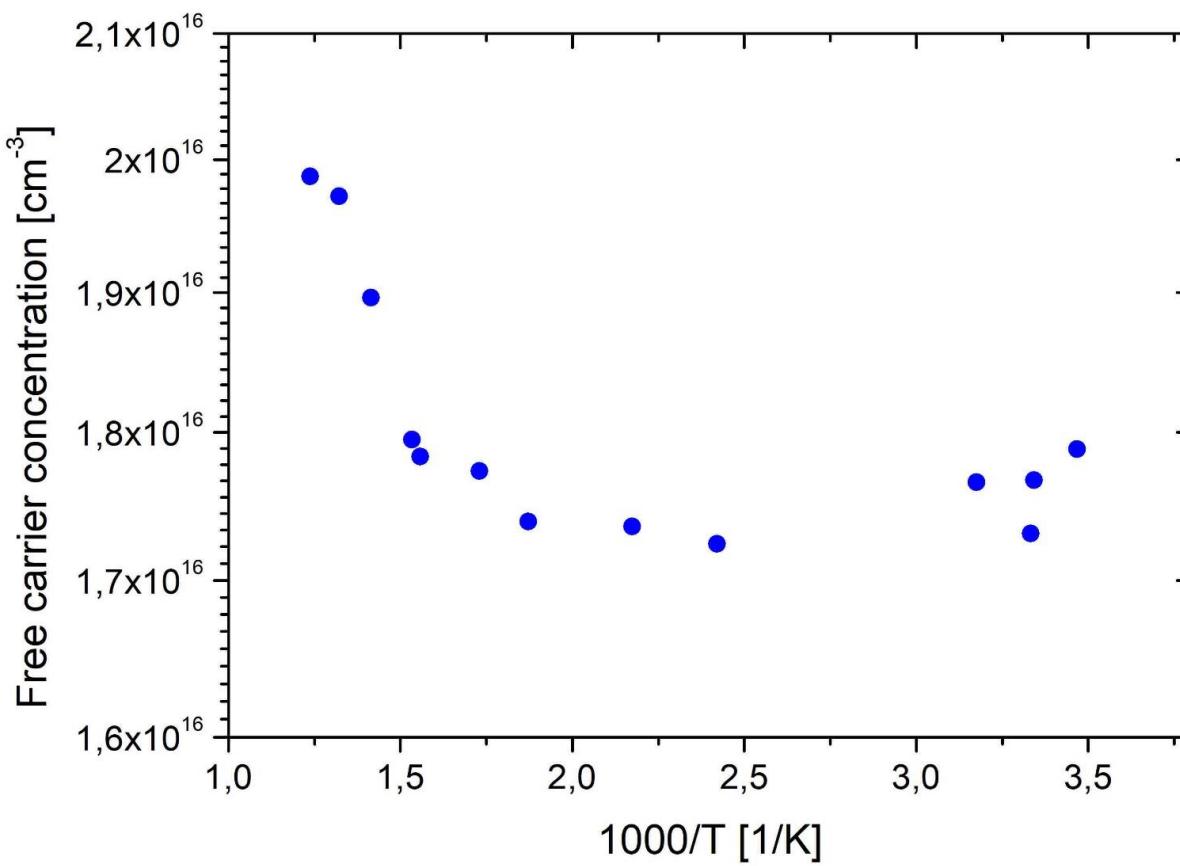


Quartz reactor



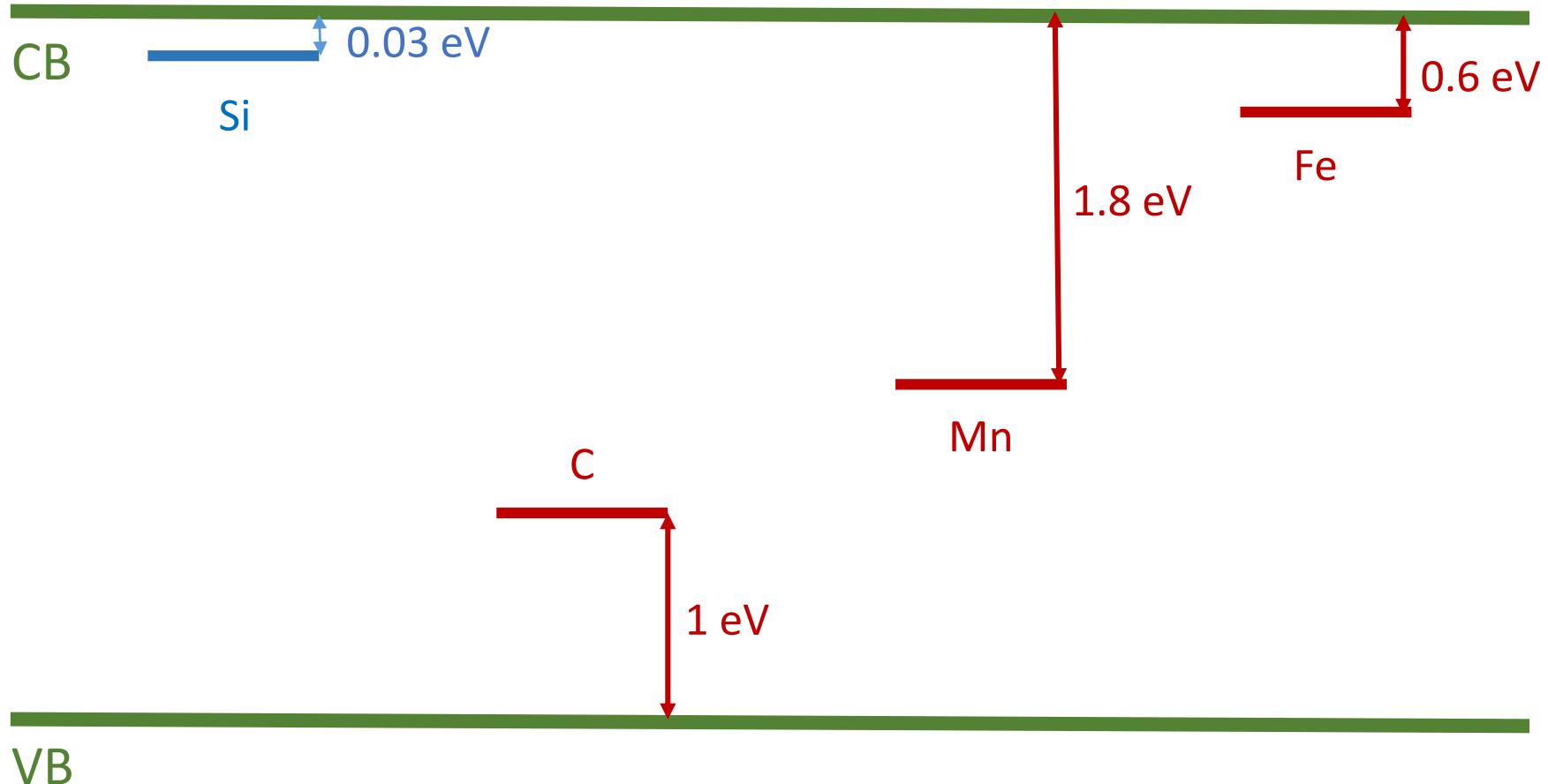
H, Fe, Cr, Ni, Ti, Cl, and B below detection limits

Undoped HVPE-GaN

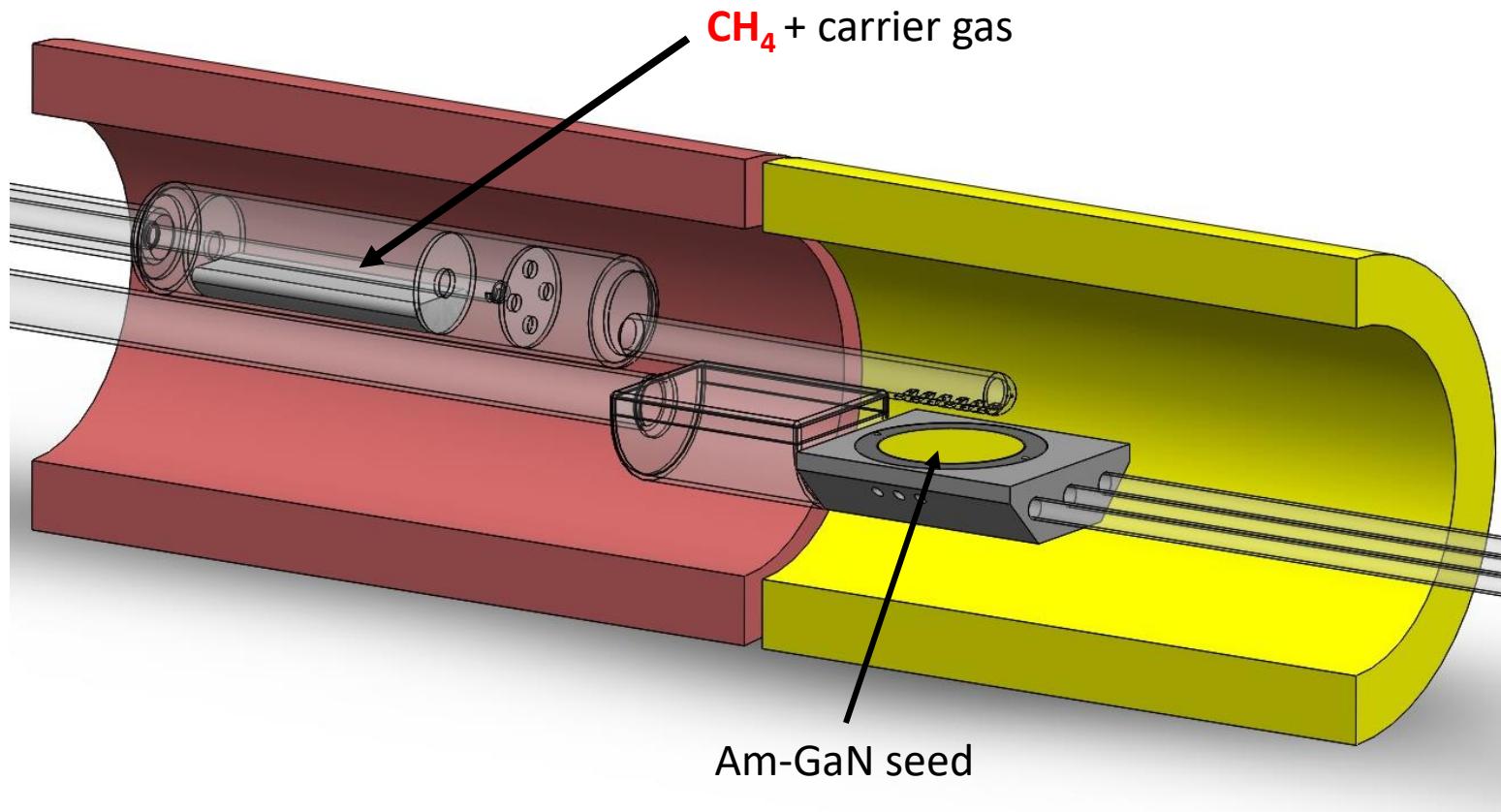


Hall measurements in Van der Pauw configuration

Dopants in GaN



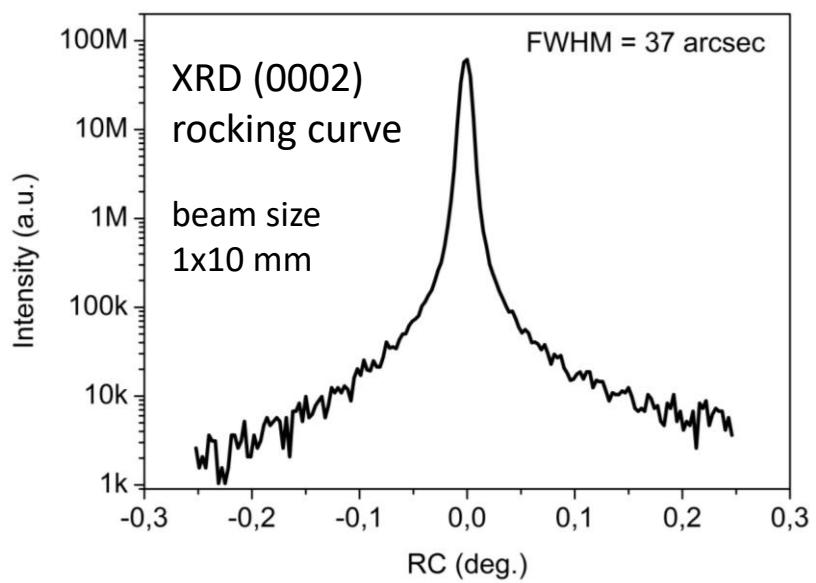
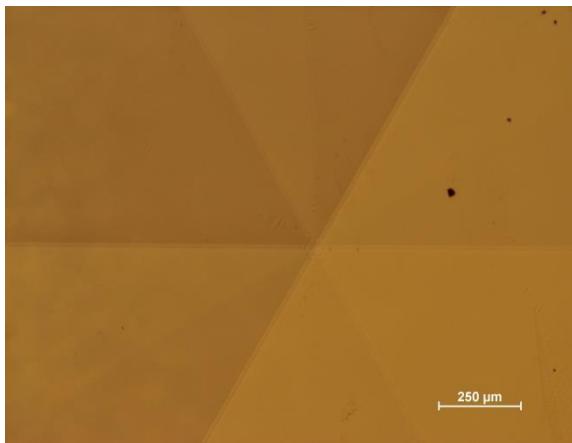
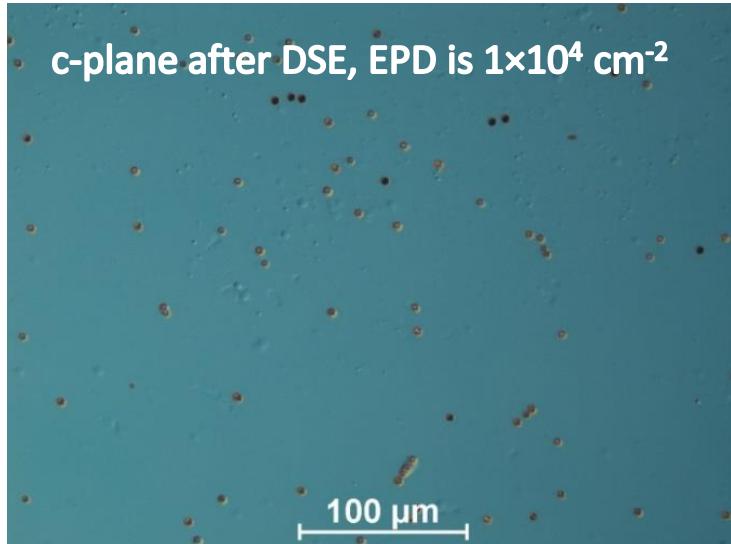
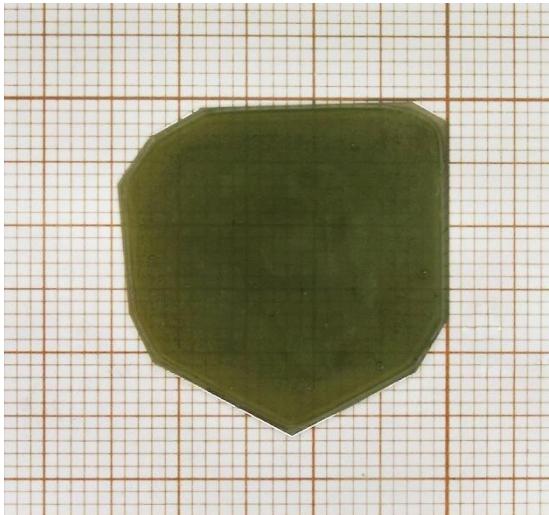
C-doped GaN



Source zone T= 850°C

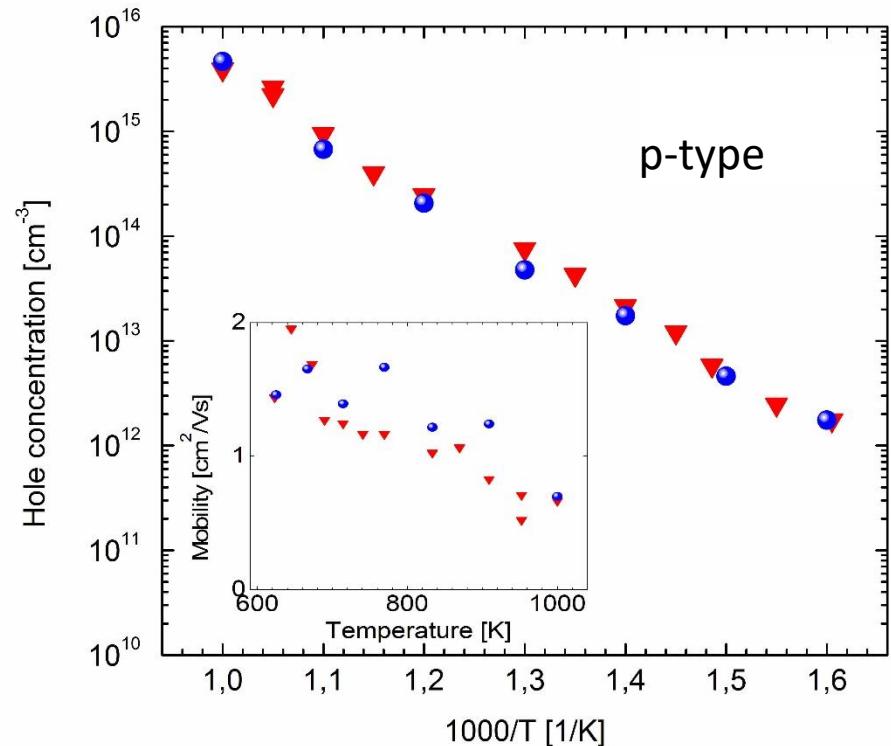
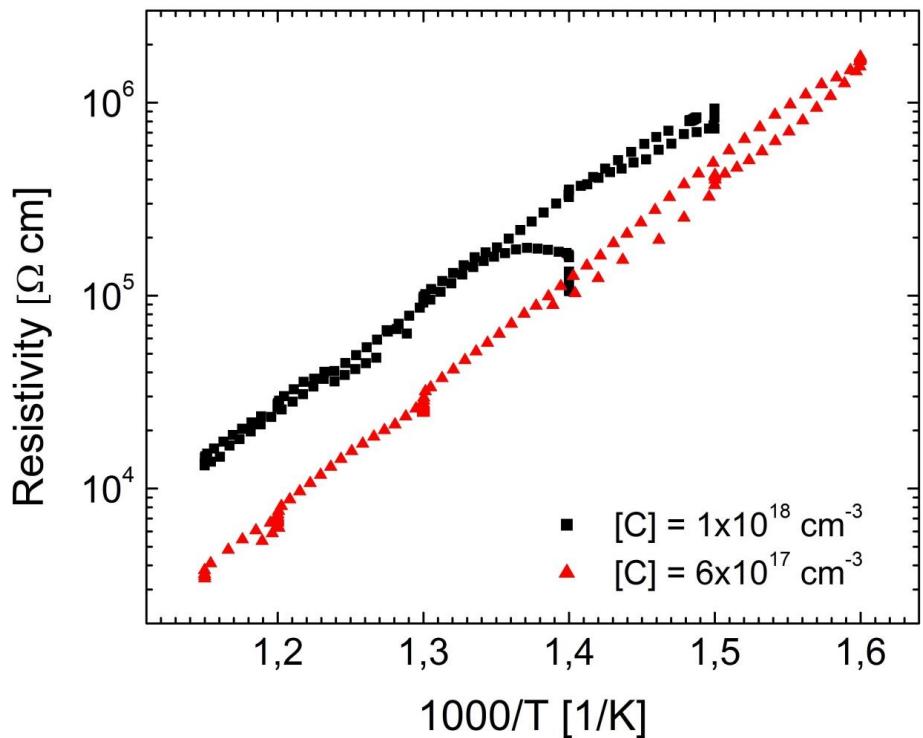
Growth zone T= 1050°C

C-doped GaN



C-doped GaN

@RT: $\rho > 10^8 \Omega\text{cm}$



Activation energy ~1 eV

C-doped GaN

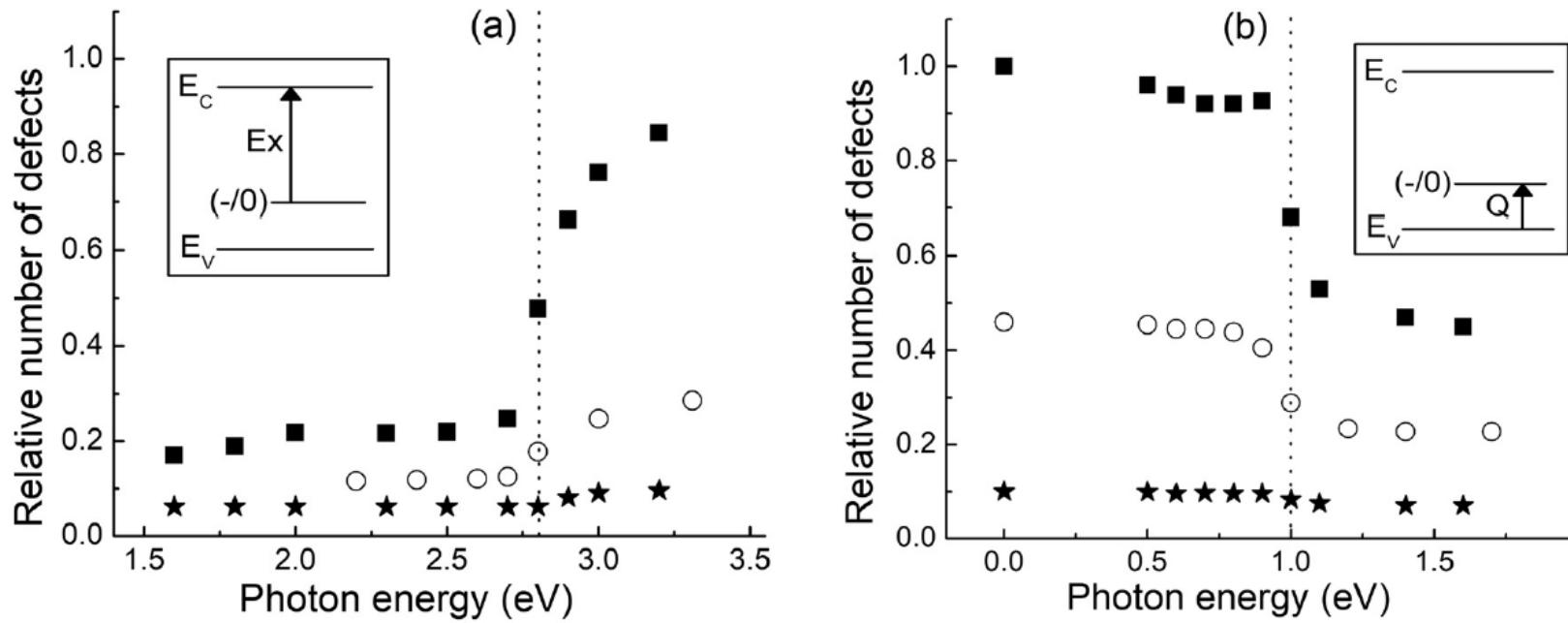
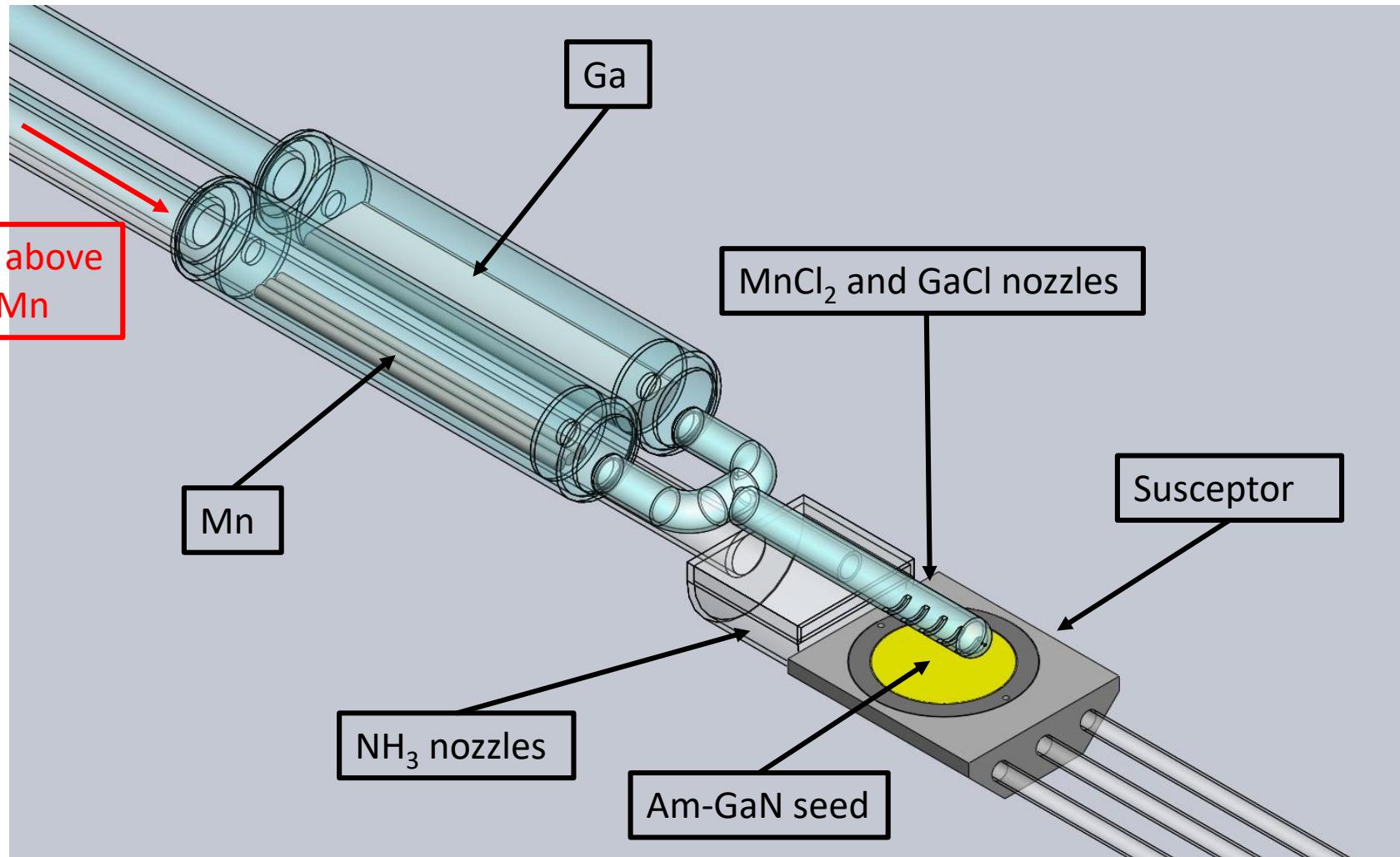


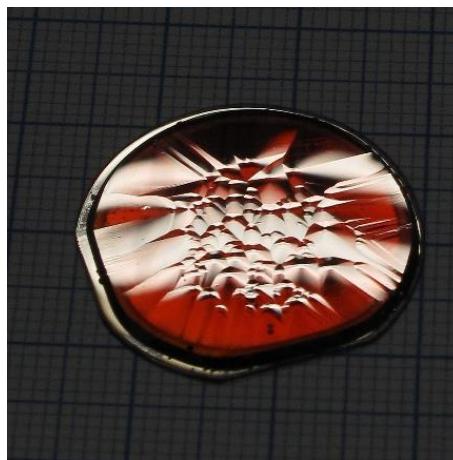
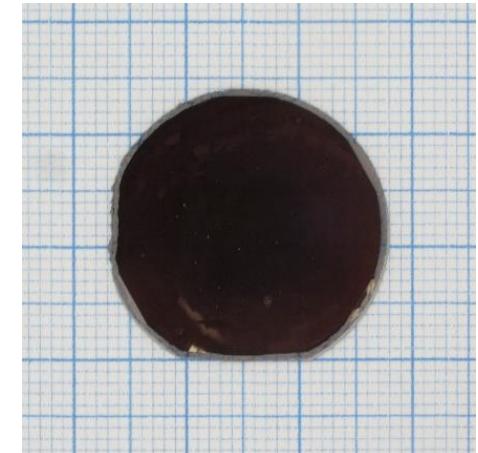
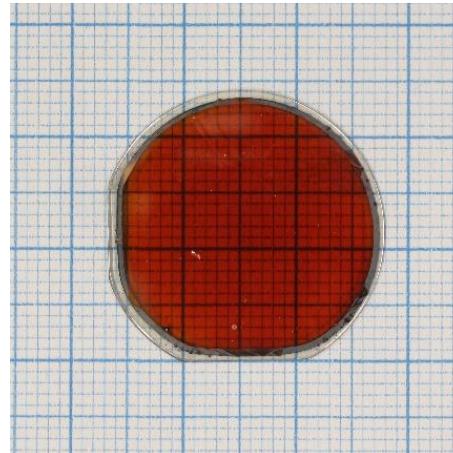
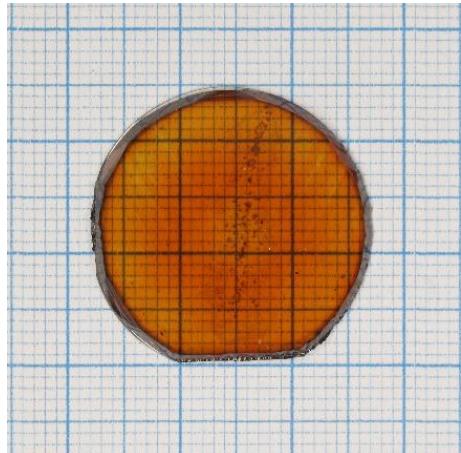
FIG. 3. Steady state photo-EPR data for 10^{19} cm^{-3} (A, square), $2.5 \times 10^{18} \text{ cm}^{-3}$ (D, circle), and $2 \times 10^{17} \text{ cm}^{-3}$ (G, star) C-doped samples for excitation (a) and quenching (b). Each point represents the relative number of defects observed after illumination with a particular wavelength. The dashed lines denote excitation and quenching threshold. Insets: Simple band model for excitation (a) and quenching (b).

Mn-doped GaN

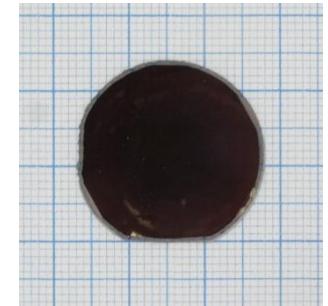
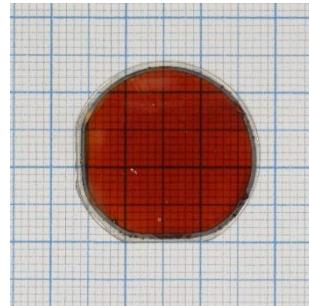
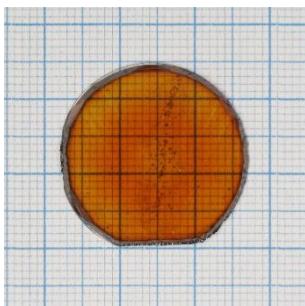


Mn-doped GaN

Increasing HCl flow above solid Mn



Mn-doped GaN

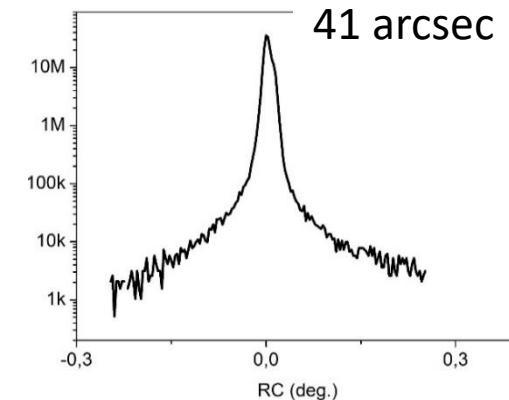
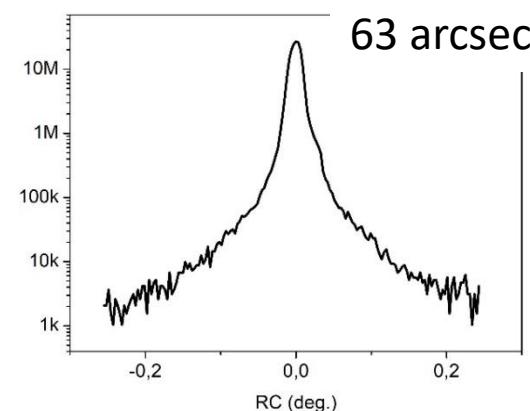
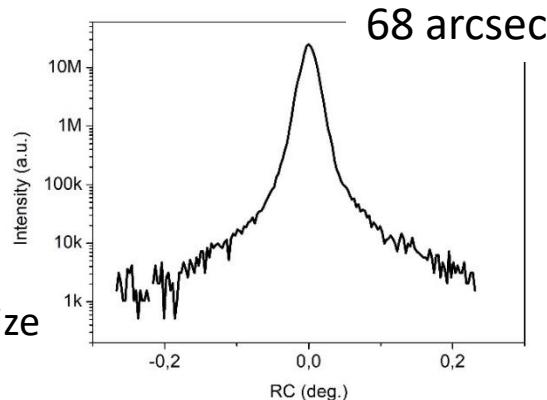


[Mn] [cm ⁻³]	3×10¹⁸	8×10¹⁸	2×10¹⁹
[Si] [cm ⁻³]	<1×10 ¹⁷	<1×10 ¹⁷	<1×10 ¹⁷

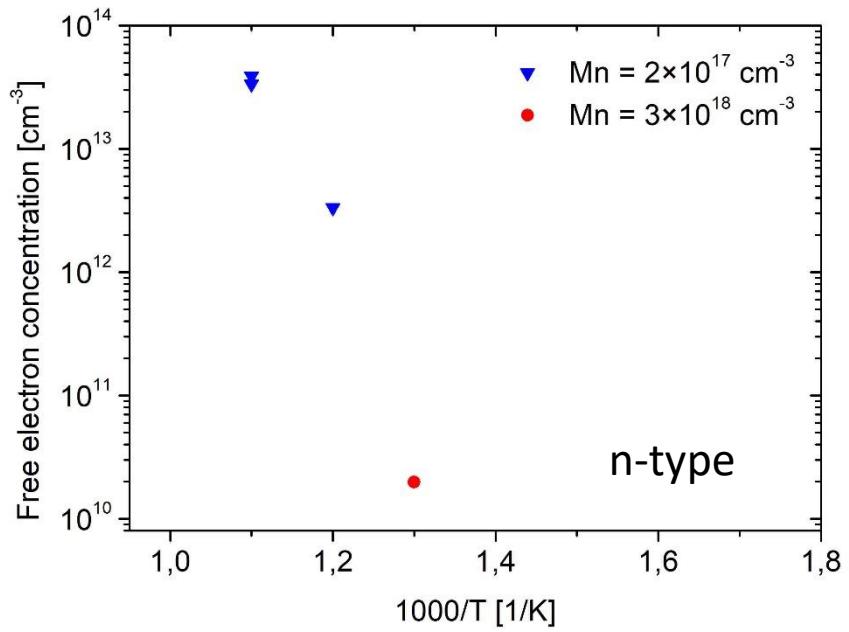
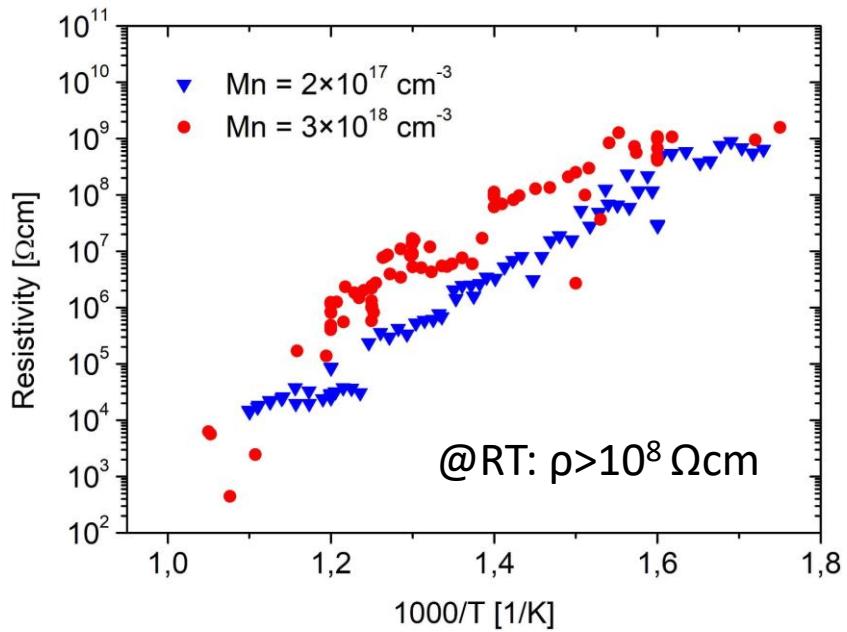
Seed: FWHM = 53 arcsec FWHM = 71 arcsec FWHM = 36 arcsec

As-grown
layer:

XRD (0002)
RC, beam size
1×10 mm



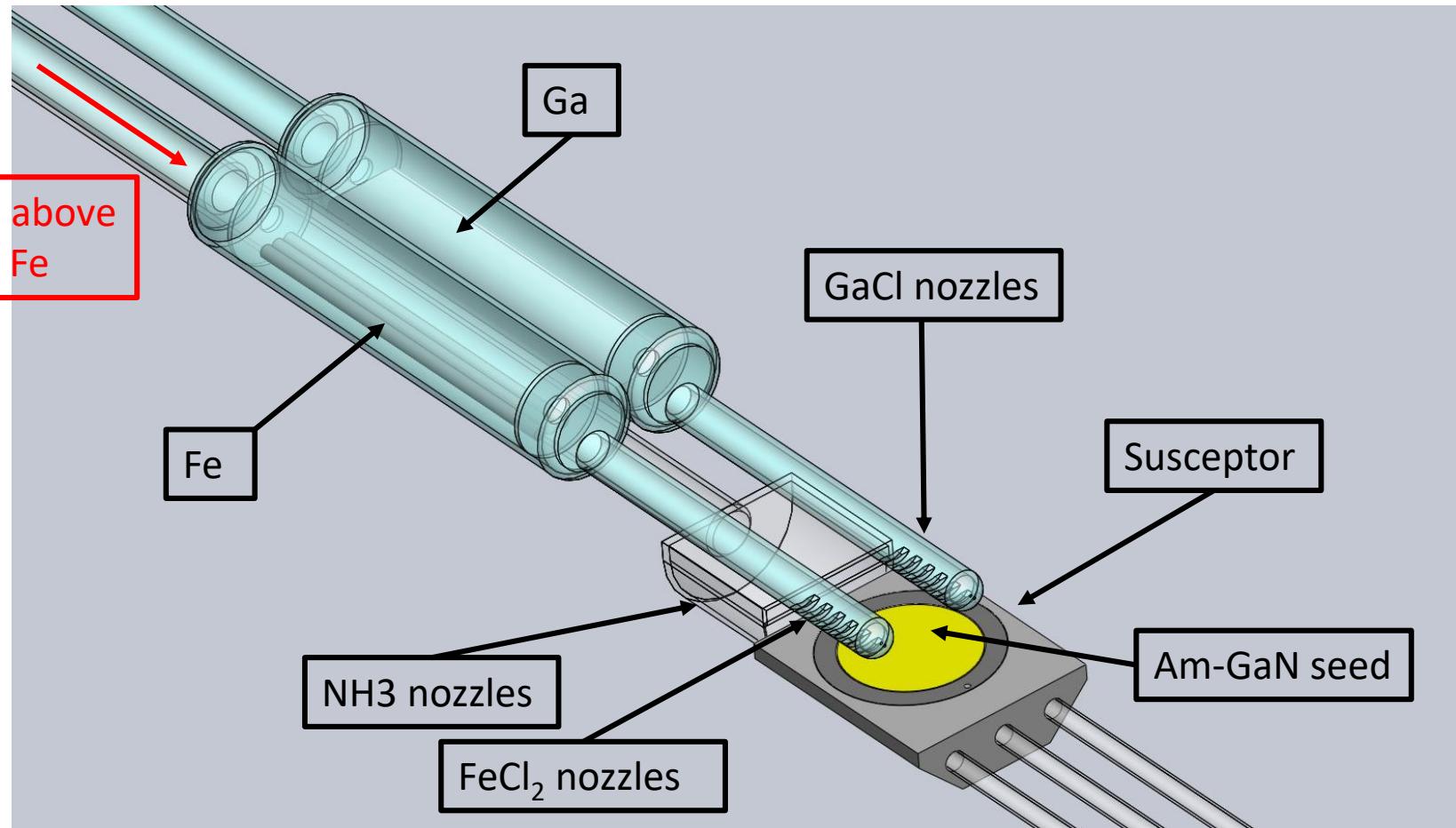
Mn-doped GaN



Activation energy ~1.8 eV

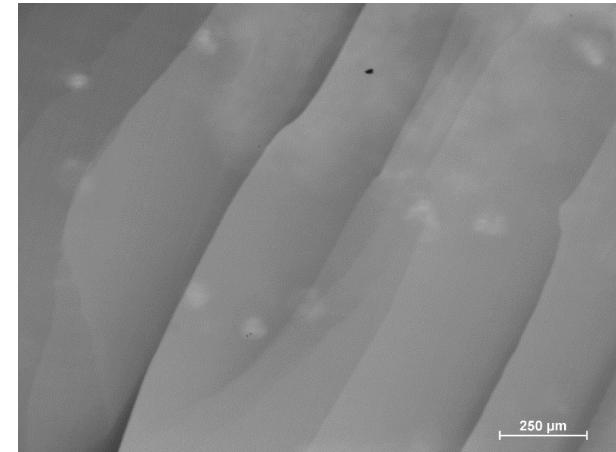
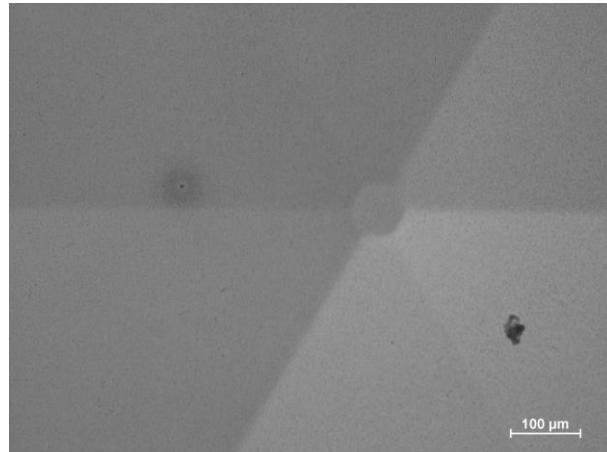
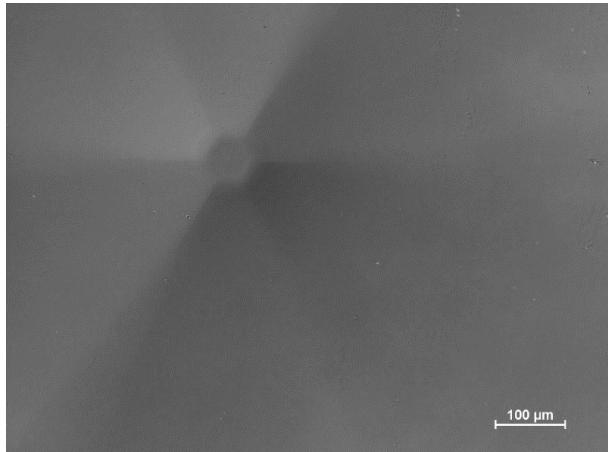
Measurements not possible for higher [Mn]

Fe-doped GaN



Fe-doped GaN

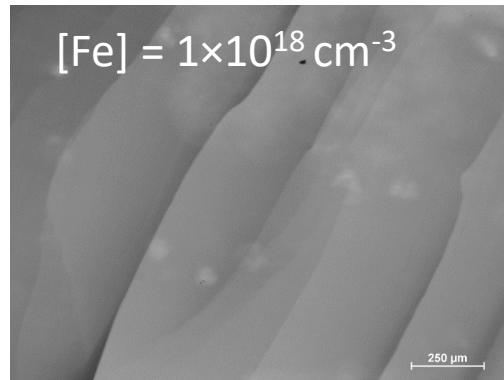
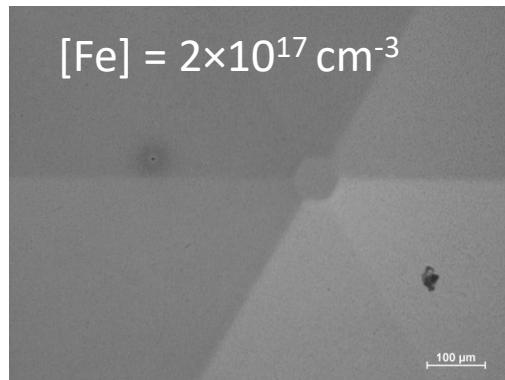
Increasing HCl flow above solid Fe



[Fe] [cm ⁻³]	6×10^{16}	2×10^{17}	1×10^{18}
[Si] [cm ⁻³]	1×10^{17}	1×10^{17}	1×10^{17}

Fe-doped GaN

Increasing HCl flow above solid Fe

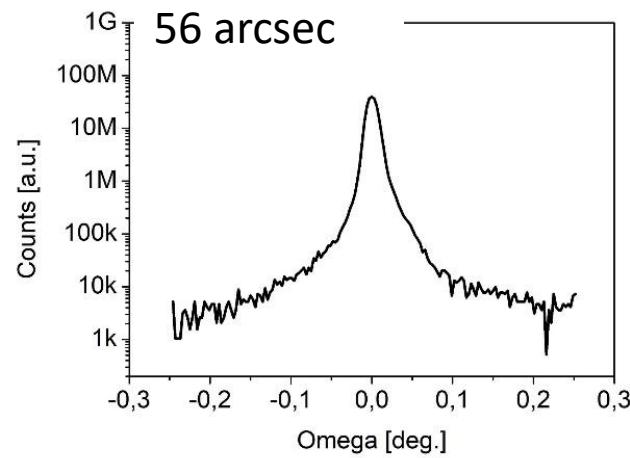
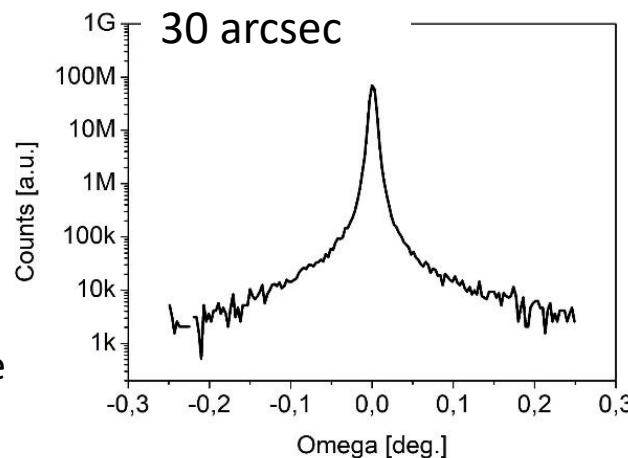


Seed:

FWHM = 30 arcsec

FWHM = 35 arcsec

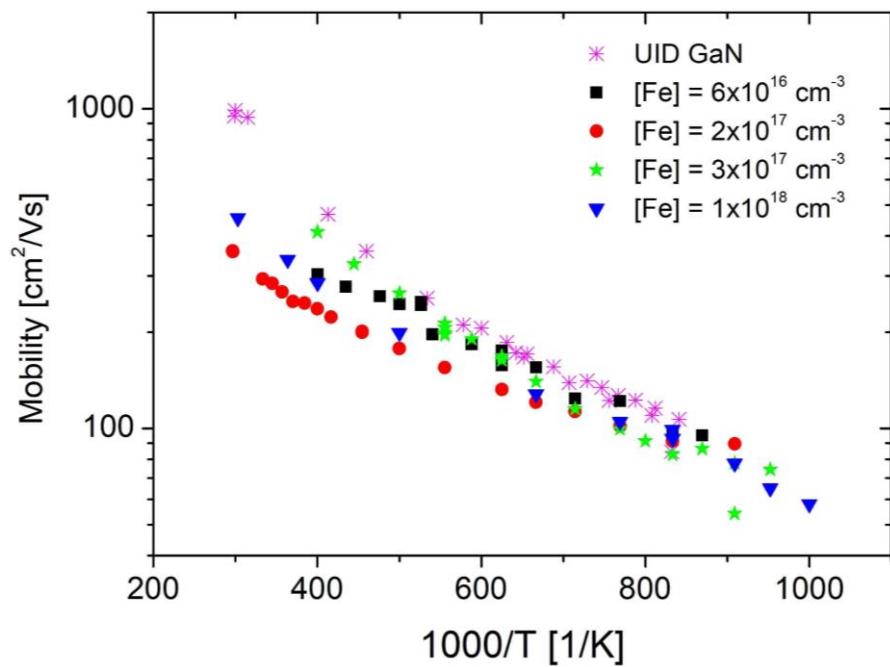
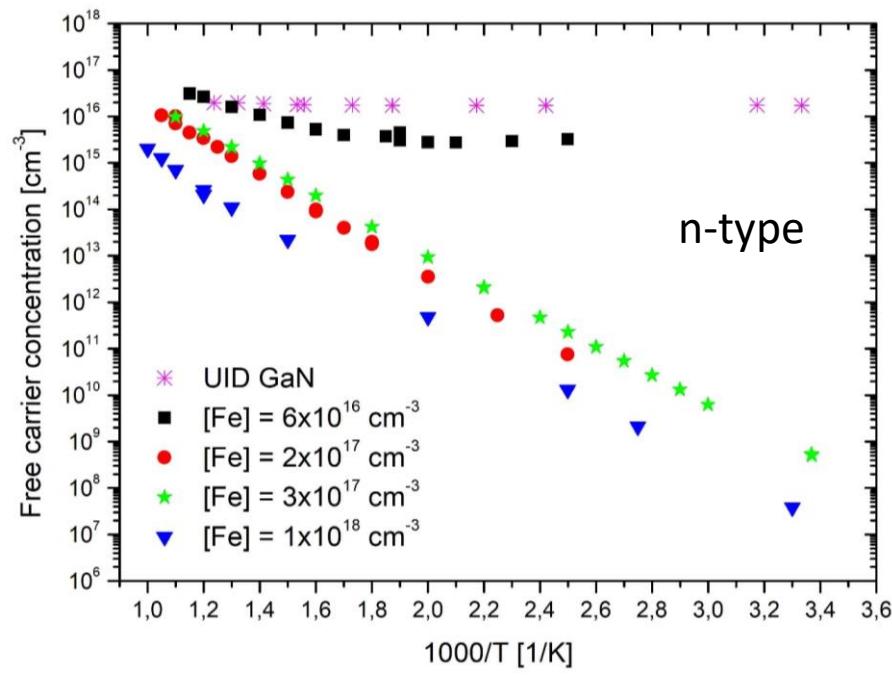
As-grown
layer:



XRD (0002)
RC, beam size
 $1 \times 10 \text{ mm}$

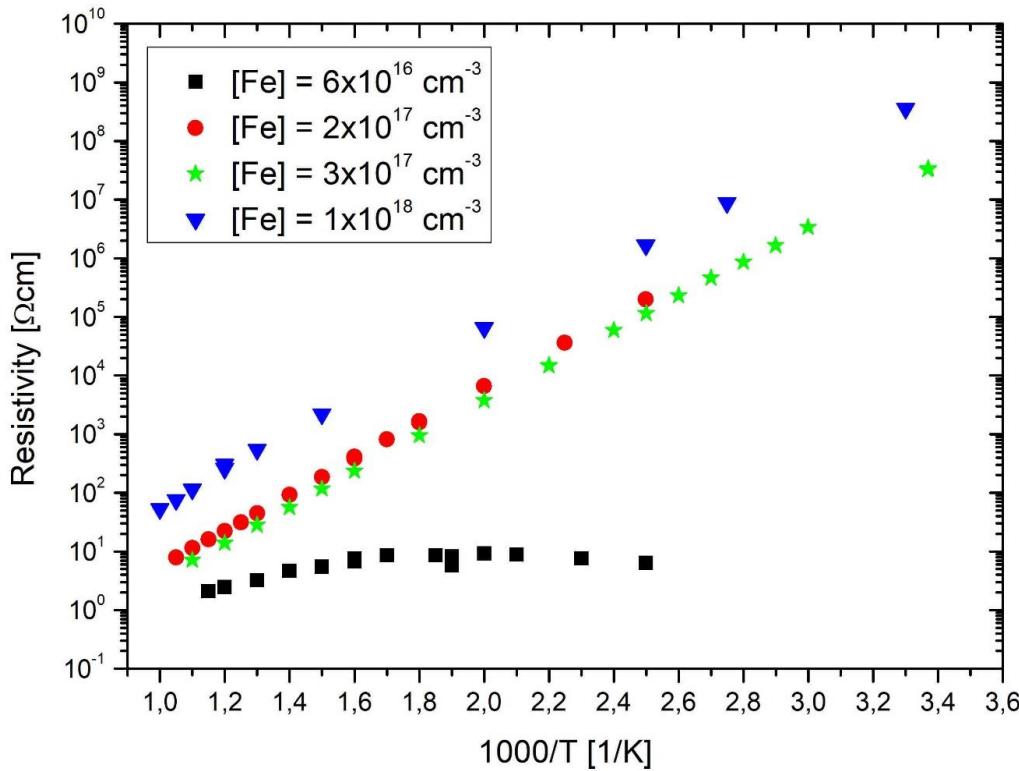
Iwinska et al., Jpn. J. Appl. Phys 58, SC1047 (2019)

Fe-doped GaN



Fe-doped GaN

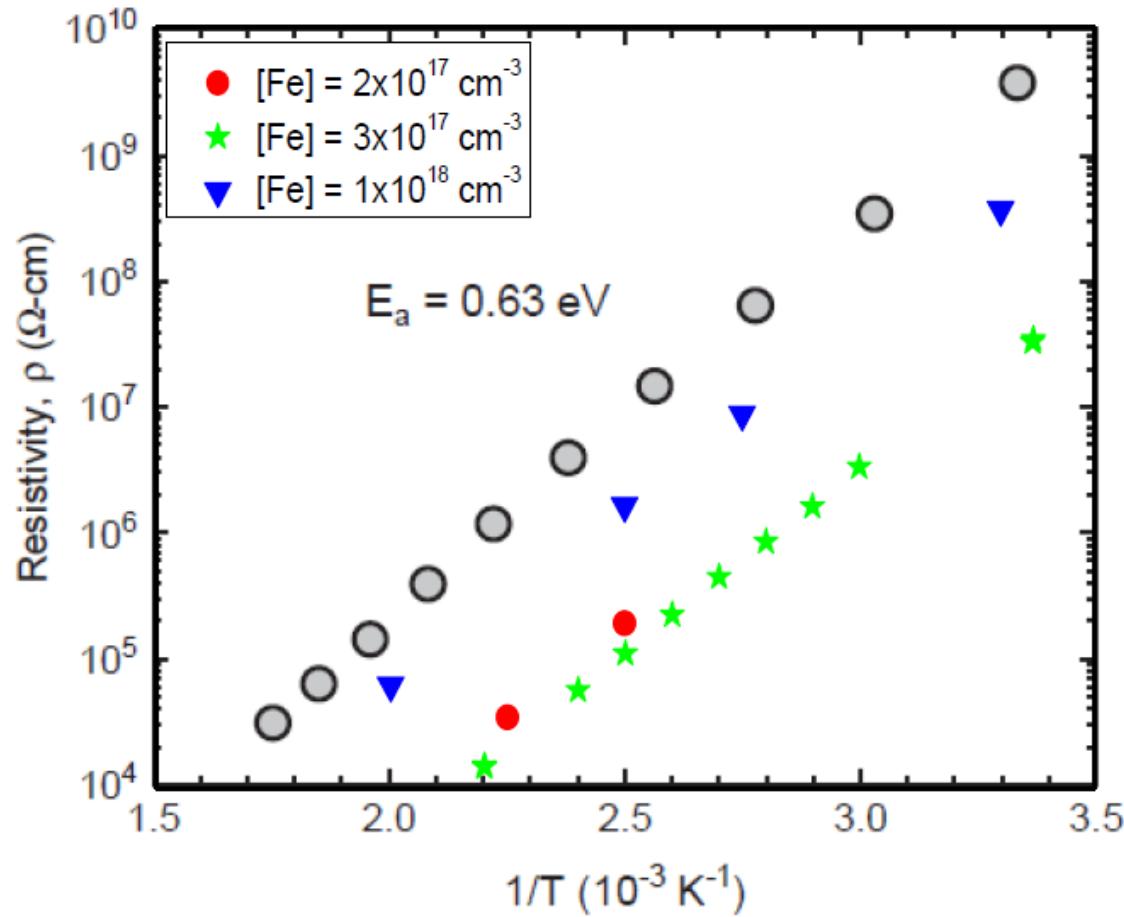
@RT: $\rho \sim 10^7 - 10^8 \Omega\text{cm}$



Activation energy $\sim 0.6 \text{ eV}$

Fe-doped GaN

- HVPE-GaN:Fe, $[Fe] = 1 \times 10^{19} \text{ cm}^{-3}$ ($[Si] = 2 \times 10^{17} \text{ cm}^{-3}$, $[C] = 1 \times 10^{16} \text{ cm}^{-3}$)



Summary

C doping

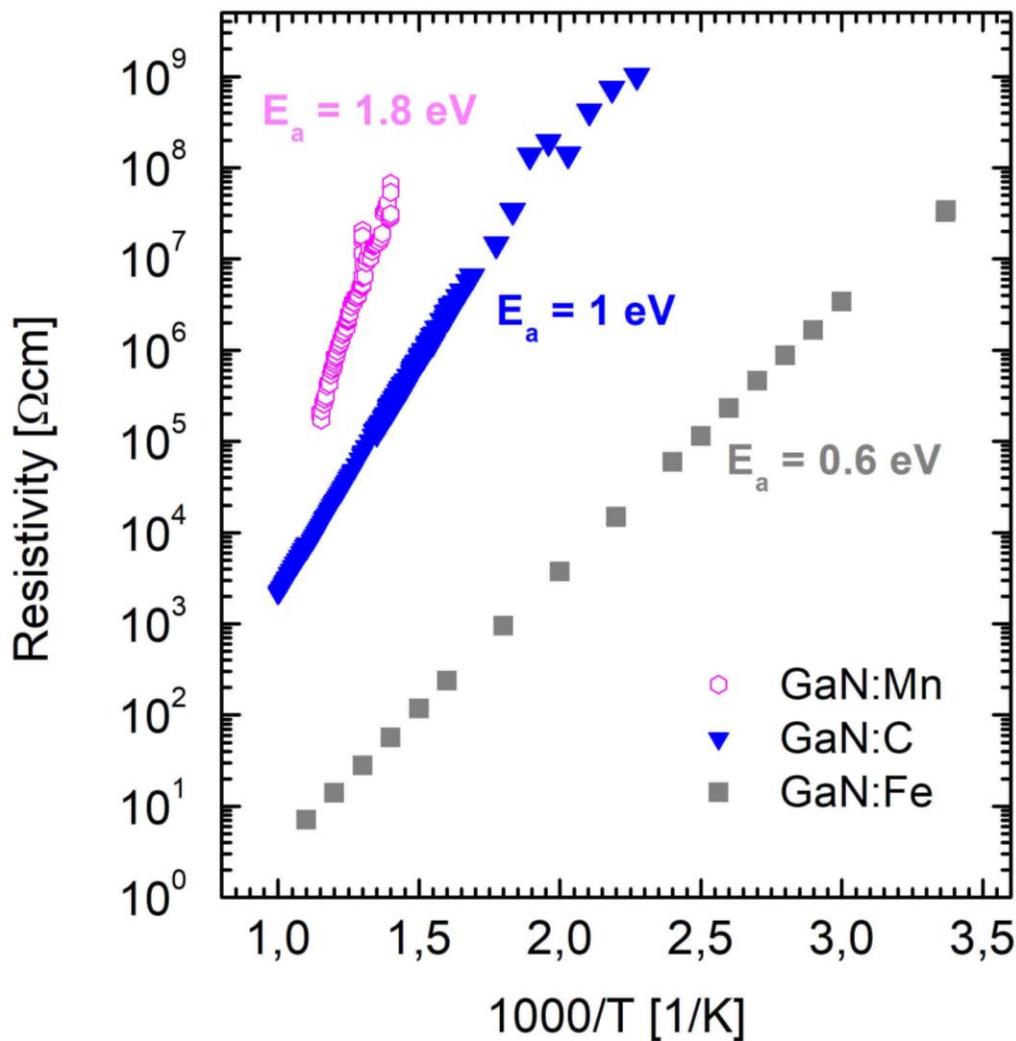
- p-type at high temperature
- highly resistive crystals
- High thermal conductivity

Mn doping

- n-type at high temperature
- highly resistive crystals

Fe doping:

- n-type
- slight deterioration of structural quality for high [Fe]
- control of free carrier concentration



M. Bockowski et al., J. Cryst. Growth 499, 1–7 (2018)

Acknowledgements

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